AEC/APC Symposium Asia 2011

- **Join us to make the move to more intelligent manufacturing -**
Wednesday, November 9, 2011
National Center of Sciences Building, Tokyo, Japan

AEC/APC Symposium Asia 2011 in Tokyo, Japan

In recent years, remarkable achievements have been realized in the field of AEC/APC which can be called the core of scientific semiconductor production technology. It is an important factor holding the key to improving the efficiency of equipment and yield enhancement in leading-edge LSI manufacturing.

Experts will present the results of advanced development in the field of AEC/APC and exchange knowledge and technology. We look forward to receiving additional abstracts and publishing more articles, including proposals for the future.

This call for papers is directed to the semiconductor and photovoltaic community, and other relevant industries, such as display, LED, lamps or glass. Other industries employing AEC/APC may also submit abstracts. The conference, focused on current challenges and future needs beyond AEC/APC, will be built around sessions of the following topics:

Important Date:

July 15
   Extended abstract submission due
Aug. 23
   Notification of abstract acceptance
Oct. 19
   Presentation materials due

Executive Committee
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Process Level Topics	Fab Level Topics

Equipment and Process Control methodology:
  Fault detection and classification
  Statistical process control
  Run-to-run control
  Enhanced equipment quality assurance
Productivity & Tool Optimizations:
  Throughput enhancement
  Uptime ratio improvement
  Cost reduction
  Non-product wafer reduction
  Maintenance
Model-based Process Control:
  Physical and chemical process model
  Model-based sensors
  Soft sensor
  Virtual metrology
  Sampling plan
Tool Data Analysis:
  Data collection
  Data acquisition
  Failure and Yield Analysis
  Statistical approaches
  Non-statistical approaches
	Data Analysis, Modeling and Visualization:
	  Data collection
	  Correlation analysis
	  Mathematical methods and model creation,
	  Novel methods of data visualization and
	  Data analysis
	Control Methods:
	  Run to run
	  Real-time control
	  Control algorithms
	Benefit of APC Application:
	  CoO
	  OEE
	  Yield
	  Productivity
	  Environment, safety and health
	APC Integration:
	  Fab automation
	  Scheduling and dispatch
	  Yield management
	  Design for manufacturing
	  Supply chain management
	IT Infrastructure for APC:
	  Fab-wide APC
	  Tool interfaces and communication
	  Innovative IT solutions
	APC Strategy:
	  Future Needs and opportunities

Online Abstract Submission Procedure:

- Prospective authors are requested to submit the abstract through web browser, consisting of exactly two pages of A4-paper size.
- The first page consists of the text (max of 1,000 words) and the second page consists of figures, supporting data, charts, photos and drawings.
- Only MS Word and JPEG/GIF files are compatible.
- The abstract must be written in English, using the online abstract submission form.
- Submit electronically before July 15, 2011.
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Information, templates, and other details are available on the website:
http://www.semiconportal.com/AECAPC/cfp.html

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